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Application No. 10/783,386
Filed: August 31, 2004
Attorney Docket No. 4262-031384

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/783,386 Confirmation No. 6408
Applicants : Larry F. Rhodes et al.
Filed : February 20, 2004
Title : Dissolution Rate Modifiers for Photoresist Compositions
Group Art Unit : 1752
Examiner : Not Yet Assigned
Customer No. : 28289

INFORMATION DISCLOSURE STATEMENT

MS Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to the requirements of 37 C.F.R. §§ 1.56, 1.97, and 1.98, Applicant hereby submits this Information Disclosure Statement, which includes a completed Form PTO/SB/08A and copies of the non-patent literature documents cited therein. Copies of the cited United States patents are not required as this application was filed after June 30, 2003.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on August 31, 2004.

Ruth A. Walkup

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Ruth A. Walkup
Signature

08/31/2004
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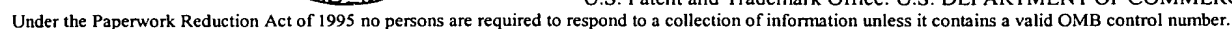
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Pursuant to 37 C.F.R. § 1.97(b)(3), no fee is believed to be due for the submission of this Information Disclosure Statement, as it is being submitted before the mailing date of a first Office Action on the merits. Nevertheless, the Commissioner for Patents is hereby authorized to charge any fees which may be required to Deposit Account No. 23-0650. One (1) original and two (2) copies of this Information Disclosure Statement are enclosed.

Respectfully submitted,

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First Named Inventor	Larry F. Rhodes
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Examiner Name	Not Yet Assigned
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				Filing Date	February 20, 2004
				First Named Inventor	Larry F. Rhodes
				Group Art Unit	1752
				Examiner Name	Not Yet Assigned
Sheet	2	of	2	Attorney Docket Number	4262-031384

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, cite and/or country where published.	T ²
	AK	JEFFREY et al., "Metal complexes of hemilabile ligands. Reactivity and structure of dichlorobis(o-(diphenylphosphino)anisole)ruthenium(II)," <u>Inorg. Chem.</u> , 1979, pp. 2658-2666, Vol. 18, No. 10.	
	AL	BADER et al., "Coordination chemistry and catalysis with hemilabile oxygen-phosphorus ligands," <u>Coord. Chem. Rev.</u> , 1991, pp. 27-110, Vol. 108.	
	AM	SLONE et al., "The Transition Metal Coordination Chemistry of Hemilabile Ligands," <u>Prog. Inorg. Chem.</u> , 1999, pp. 233-350, Vol. 48.	
	AN	REICHMANIS et al., "Chemical Amplification Mechanisms for Microlithography," <u>Chem. Mater.</u> , 1991, pp. 394-407, Vol. 3.	
	AO	HAMAD et al., "Fluorinated Dissolution Inhibitors for 157 nm Lithography," <u>Advances in Resist Technology and Processing XIX, Proceedings of SPIE</u> , 2002, pp. 477-485, Vol. 4690.	
	AP	HAMAD et al., "Evaluation of Fluorinated Dissolution Inhibitors for 157 nm Lithography," <u>Advances in Resist Technology and Processing XX, Proceedings of SPIE</u> , 2003, pp. 558-568, Vol. 5039.	
	AQ	WILLSON et al., "Fluorinated Polymers and Dissolution Inhibitors for 157nm Microlithography," <u>Polymeric Materials: Science & Engineering</u> , 2002, pp. 396-397, Vol. 87.	
	AR	CONLEY et al., "Dissolution Inhibitors for 157 nm Lithography: A Progress Report," <u>J. Photopolym. Sci. Technol.</u> , 2002, pp. 613-617, Vol. 15, No. 4.	
	AS	KUMARESWARAN et al., "Hydrovinylolation of Norbornene. Ligand-Dependent Selectivity and Asymmetric Variations," <u>Org. Lett.</u> , 2003, pp. 4345-4348, Vol. 5, No. 23.	
	AT	TRAN et al., "Metal-Catalyzed Vinyl Addition Polymers for 157 nm Resist Applications. 2. Fluorinated Norbornenes: Synthesis, Polymerization, and Initial Imaging Results," <u>Macromolecules</u> , 2002, pp. 6539-6549, Vol. 35.	

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